

F-6971

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U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
							Yes No
OTHER INFORMATION DISCLOSURE CITATIONS (Including Author, Title, Date, Pertinent Pages, Etc.)							
		1997 - X-ray Reflectometer for the Diagnostics of Thin Films During Growth, U. Niggemeier, K. Lischka, W. M. Plotz and V. Holy, Journal of Applied Crystallography, Volume 30, Pages 905-908					
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